

Protocol to study wavefront preservation capabilities of reflective X-ray optics with coherent synchrotron light

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Abstract

Wavefront preservation of reflective X-ray optics, i. e., homogeneity and coherence properties of the reflected beam, are of crucial importance for their application in combination with high-brilliance synchrotron light sources. In order to compare the performance of optical elements in a quantitative manner, a protocol has been established using the Talbot effect to access the coherence properties of the reflective beam as well as long propagation distance imaging to study its homogeneity. The basic idea is to operate in a single-bounce geometry: a high-resolution imaging detector translated at short propagation distances along the beam is used to measure the visibility of a diffraction grating in transmission geometry placed close to the mirror under study. The change of the fringe visibility as a function of distance between the grating and the detector gives access to the angular source size. A second high-resolution imaging detector at longer propagation distances of up to several meters allows one to measure the homogeneity of the beam. This article outlines the concept as realized at beamline ID19 of the European Synchrotron Radiation Facility, gives insight into some of the technical details to be considered for implementation at other facilities and ends with an example application: the study of a W/B₄C multilayer mirror.

Keywords: X-ray optics, multilayer mirrors, X-rays, coherence, X-ray monochromators, X-ray imaging, X-ray phase contrast, Talbot effect, synchrotron radiation

1. Introduction

2 Reflective optics are widely used in combination with hard X-rays, e. g., Bragg-reflection
3 on single-crystals or reflection on flat multilayer mirrors for monochromatization purposes,

4 or total reflection on (single-coated) X-ray mirrors to suppress higher harmonics for exam-
5 ple of an undulator source [1]. Recently, reflection on curved multilayer-coated KB-mirrors
6 has been successfully used to reach sub-100 nm focusing of hard X-rays [2].

7 However, as any optical element, reflective X-ray optics show deviations from their ideal
8 behavior. These deviations originate from various sources, such as roughness or slope er-
9 rors of reflective surfaces and interfaces, effects of dynamical diffraction (in the case of
10 crystal optics), contamination of the surfaces, etc., and they can affect any of the perfor-
11 mance parameters of the devices, e. g., the homogeneity (flatness) of the beam profile at the
12 sample position, the smoothness of the wavefront phase profile, and the coherence proper-
13 ties of the beam.

14 An example of wavefront modification caused by a reflective optical element is the beam
15 profile after reflection on a multilayer mirror [3]. Commonly, this reflected beam profile
16 shows a typical stripe modulation in combination with a certain loss of coherence proper-
17 ties. Such degradation of the wavefront can be detrimental for phase-sensitive imaging
18 techniques [4], [5], [6]. Attempts to improve the wavefront preservation capability of
19 multilayer mirrors require quantitative approaches to characterize the degradation of the
20 wavefront due to reflection on such mirrors.

21 This article will introduce a protocol which has recently been established to compare
22 multilayer mirrors consisting of different material compositions [3], [8], [9], or that were
23 made by varying coating parameters [10], or using different coating facilities [11] at beam-
24 lines 32-ID (Advanced Photon Source APS, USA) as well as ID06 and ID19 (European
25 Synchrotron Radiation Facility ESRF, France). The basic idea is to measure at short propa-
26 gation distances the visibility of a phase grating which is placed close to the reflective
27 optical element. The change of the visibility at different Talbot distances gives access to
28 the vertical and horizontal angular source size [12], [13]. At larger propagation distances,
29 modifications of the wavefront are transformed into intensity modulations and hence, al-
30 low one to depict the homogeneity of the reflected beam [14]. Besides the technical details
31 of the implementation, a few issues worth considering when implementing the protocol at
32 other facilities are described together with an example application.

33 2. Experiment

34 The experimental setup as used at beamline ID19 of the ESRF is depicted in Figure 1
35 [15]. Optics characterization studies are commonly performed at ID19 with the storage
36 ring operating in the so-called 4-bunch mode, because of beamtime availability issues. In
37 this mode the storage ring electron current is 40 mA, i. e., only 20% of the maximum user-
38 mode value. The two U32 undulator insertion devices of the beamline are combined in
39 order to achieve a sufficient photon flux density. A diamond window placed close to the
40 front-end is used to suppress the softer part of the spectrum. The vertical reflecting double-
41 crystal monochromator 140 m downstream of the source is applied to select a wavelength
42 of 18 keV to illuminate the optical element under study. The photon energy is selected as
43 by experience a majority of high-resolution X-ray imaging experiments using synchrotron
44 light are performed using energies from a range around this value. Illuminating with a
45 well-defined energy subsequently reduces the alignment effort, i. e. it is sufficient to rock
46 the reflective optics while tracking the reflected beam with a large phosphor screen and a
47 video camera. Furthermore, the heat load downstream of the crystal monochromator is
48 negligible, allowing one to mount the optics under test in air without further cooling. In this
49 configuration, the degradation of the wavefront with respect to the beam as only reflected
50 by the silicon crystals of the monochromator is measured.

51 The mount for the optical element is shown in Figure 2. A simple aluminium plate is used
52 as a base, bars are located upstream and downstream of the element in a shiftable manner.
53 They can be tightened to the plate for fixation of the optics without introducing mechanical
54 stress. The mount is fixed on a double-cradle system (Huber Diffraktionstechnik GmbH
55 & Co. KG, Germany) in order to correct the roll and chose the angle of incidence. This

56 setting is then mounted on the sample manipulator of the high-resolution tomograph of the
57 ID19 beamline. The manipulator is used to align the reflective optics with respect to the
58 incoming beam.

59 A phase grating is positioned downstream of the optics (typically approximately 10 cm
60 away) on translation stages to align the grating with respect to the beam and move it out
61 of the beam for taking reference images, cf. Figure 2. The high-resolution tomograph is
62 additionally equipped with a 1 m high-precision linear axis in order to translate an X-ray
63 detector along the beam (frequently used in combination with holotomography [4]). Due
64 to the fact that ID19 operates a single-bounce vertically deflecting multilayer as monochro-
65 mator as well, the entire tomograph including the detector axis can be tilted by several
66 degrees around a horizontal transverse axis; the detector translation can thus be aligned to
67 move parallel to a beam reflected upward by a multilayer. This configuration is used to
68 measure the visibility of the phase grating at different distances. On instruments without a
69 tiltable stage, the detector can be translated along the beam by adding another linear stage
70 for vertical translation [11]. A second high-resolution detector is positioned further down-
71 stream; in the case of ID19 it is located on the medium-resolution tomograph, 6.1 m from
72 the reflective optics tested.

73 In order to study the coherence properties by means of Talbot imaging, it is beneficial to
74 operate with shorter propagation distances between the grating and the first imaging detec-
75 tor and with the grating close to the optical element: the visibility of the phase grating in
76 the images is determined by the coherence of the impinging wavefront but image analysis
77 is also affected by the accuracy of the flat-field correction [6]. Simply speaking: measuring
78 the coherence properties close to the reflective optical element allows one to work with a
79 rather homogeneous beam profile and hence, suppresses unwanted artifacts due to imper-
80 fect flat-field corrections [7]. Furthermore, the influence of potential angular instabilities
81 of the investigated optical element is reduced. Commonly, the visibility is scanned starting
82 from a propagation distance around zero to the second Talbot distance in equidistant steps
83 that are much smaller than the Talbot distance. Compared to measuring only at the Talbot
84 distances (i. e., the visibility maxima), this increases to a certain degree the sensitivity of
85 the characterization. For example, focusing effects can shift the maximum visibility away
86 from the Talbot distance (see as well Section 5.2). In order to measure the homogeneity of
87 the reflected wavefront, a second detector is positioned several meters downstream (with
88 the phase grating and first detector out of the beam). Phase distortions introduced to the
89 wavefront due to the reflection on, e. g. an imperfect surface are converted into intensity
90 modulations due to the long propagation of the beam [14], [16].

91 3. Phase Grating

92 The test object was made from a 0.25-mm-thick silicon $\langle 100 \rangle$ substrate. The grating
93 pattern, a mesh of square dots on a Cartesian grid, was exposed into a resist layer of poly-
94 methyl methacrylate (PMMA) using a Vistec EBPG 5000 plus electron-beam lithography
95 system (Vistec Electron Beam GmbH, Jena, Germany) at 100 keV electron energy [17].
96 After development the resist pattern was transferred into a 25-nm-thick chromium layer
97 by dry etching in a Cl_2/CO_2 plasma [18]. This layer served as a hard mask for the pattern
98 transfer into the silicon substrate using a reactive ion etching process in a $\text{SF}_6/\text{C}_4\text{F}_8$ plasma.
99 The resulting structures are 5 μm deep and have nearly vertical side walls, cf. Figure 3. At
100 a photon energy of 18 keV, this corresponds to a phase shift of 0.68 rad (i. e., $\approx \pi/5$), while
101 the absorption in the structures remains negligible (0.6%).

102 4. Data Processing

103 For the data processing, an ESRF inhouse developed code is applied which has already
104 been described in detail elsewhere [19]. The approach of first integrating the image of

105 the phase grating horizontally and vertically in order to achieve line profiles of the inten-
106 sity, with a reduced noise level compared to individual section profiles, was found to be
107 very robust under different experimental conditions [9], [11]. The visibility is then deter-
108 mined by Fourier analysis. Alternative processing concepts, in which the visibility is first
109 calculated locally and then the mean over all visibility values is determined, or using a
110 two-dimensional Fourier transform, were found to be more sensitive to noise.

111 5. Considerations

112 A few issues frequently appear when studying the wavefront preservation capabilities
113 by means of Talbot imaging and long propagation distance imaging. For the reader who
114 is interested in implementing the protocol described in this article, the major issues which
115 can occur are briefly described below.

116 5.1. Storage Ring

117 The measured visibility of the phase grating can vary drastically during and after a ma-
118 chine refill (i. e. the storage ring is not operated in top-up mode). An extreme example is
119 shown in Figure 4 (top) where a refill occurred during a visibility scan (the storage ring
120 operated in the so-called 4-bunch mode). The inset shows the approximated visibility plot
121 before and after the refill, the visibility drops significantly from 0.25 to 0.20 due to the
122 refill.

123 5.2. Wavefront curvature

124 The data processing approach as described in Section 4 is strictly valid only in case of
125 a parallel beam. The finite distance to the source, as well as any focusing effects induced
126 by beamline optics or the element tested cause deviations from this condition. A divergent
127 beam magnifies the image for larger propagation distances and hence, artificially increases
128 the size of the grating structures as projected onto the detector. Frequently, the modulation-
129 transfer function of the detectors used increases for lower frequencies, i. e. the enlarged
130 image determines an artificially increased visibility. The effect of the distance from the
131 source and of focusing beamline optics with known focal lengths can be corrected. How-
132 ever, in the case of strongly bent reflecting optics which diverge or focus the beam, the
133 protocol described in this article will not deliver correct results.

134 5.3. Detector

135 The indirect high-resolution detectors commonly used are based on visible light mi-
136 croscopy combined with scintillator screens [20]. The spatial resolution of a visible light
137 microscope drops from the center of the image towards the border. This can affect as well
138 the measured visibility as shown in Figure 4 (bottom): regions-of-interest (ROI) of an grat-
139 ing image at a fixed propagation distance were analyzed. The ROIs were chosen along a
140 horizontal line in the middle of the field-of-view. The analyzed ROI should therefore be
141 chosen as close as possible to the center of the field-of-view. Furthermore, the ROI should
142 be kept the same at least during one measurement campaign.

143 5.4. Reproducibility

144 Due to the aspects mentioned in the previous three sections, it is recommended to have
145 a calibration sample which is measured during each individual measurement campaign.
146 By doing so, results from different campaigns are comparable to a certain degree, i. e. the
147 reproducibility of the results is verified.

148 6. Example

149 W-based multilayer mirrors are frequently used for monochromatization in combina-
150 tion with hard X-ray imaging at synchrotron beamlines, e. g., TOMCAT at the Swiss Light
151 Source [21], BAMline at BESSY-II, Germany [22], TopoTomo at ANKA, Germany [23],
152 2-BM of the APS, USA [24], or ID19 at the ESRF, France [15]. Here we present measure-
153 ments on a W/B₄C multilayer mirror produced by means of magnetron sputtering at the
154 ESRF multilayer deposition laboratory [25]. The multilayer consists of 120 bilayers with a
155 period (d spacing) of 2 nm, which have been deposited on a Si substrate (General Optics,
156 USA, 100 mm × 20 mm × 18 mm). The ratio Γ between the thickness of each W layer
157 and the bilayer period d was set to a nominal value of 0.5. Further details on the coating
158 parameters have already been reported [10, 11].

159 The experiment was carried out at the ESRF beamline ID19 as described above. The
160 multilayer was illuminated with photons of 18 keV energy. A phase grating with a pitch of
161 6 μm was used. The first detector operated with 0.70 μm effective pixel size (10× objective
162 with 0.3NA combined with a 2× eye-piece), a scan of the visibility was performed for
163 propagation distances ranging from 100 mm to 840 mm. The second detector at 6.1 m fixed
164 propagation distance operated with an effective pixel size of 0.75 μm (10× objective with
165 0.3NA combined with a 2× eye-piece). The results are depicted in Figure 5. The angular
166 source size as derived from the visibility at the two given Talbot distances is: 1.54 μrad
167 (horizontal) × 1.69 μrad (vertical) (without multilayer reflection: 1.48 μrad × 1.28 μrad).
168 As can be expected, the horizontal source size remained rather unchanged while the vertical
169 source size is affected by the vertically deflecting multilayer mirror. The picture of the beam
170 profile in Figure 5 has been normalised to the mean gray-value. The profile plot reveals a
171 rather strong modification with respect to the flat incoming beam with peak-to-valley values
172 of up to 50%.

173 7. Summary

174 A protocol to study wavefront preservation capabilities of reflective X-ray optics has
175 been described. It is relatively simple to implement into existing imaging instruments at a
176 synchrotron beamline. While the beamline ID19 of the ESRF is specially well-suited for
177 this kind of studies due to its coherence properties, the long experimental hutch and the tilt-
178 able high-precision linear stage for the detector, the protocol has already been successfully
179 applied at other stations such as 32-ID (APS) and ID06 (ESRF) as well [10], [11], [19].

180 The characterization of optical elements in transmission mode is possible with this pro-
181 tocol, as long as these elements do not substantially change the wavefront curvature (cf.
182 Section 5.2). So far, single crystal Be windows were studied [26].

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272 **Figures**

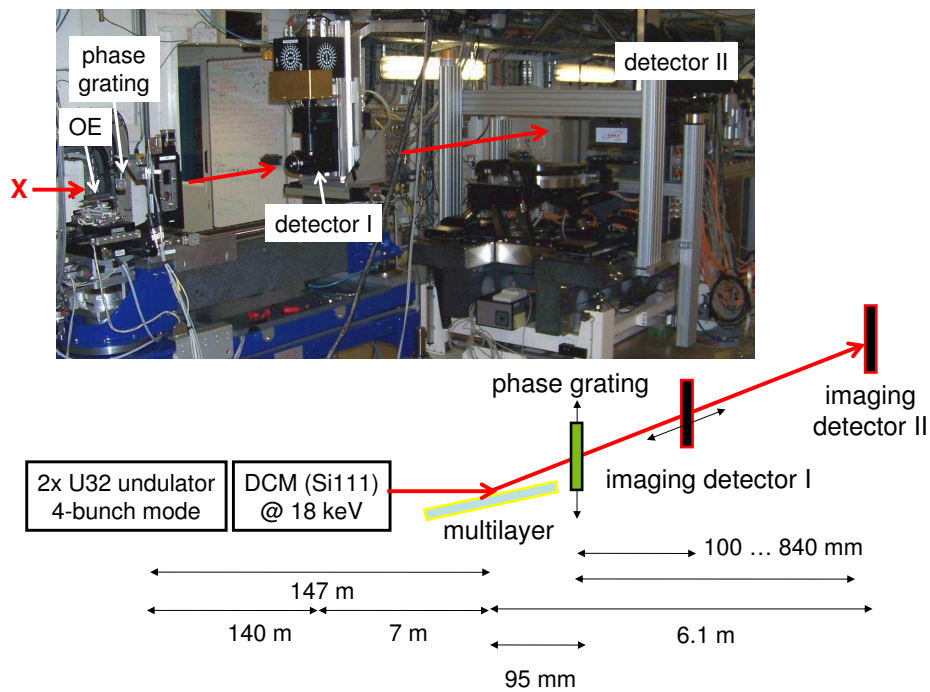


Figure 1: [2-column-span, color online only] The experimental setup as typically used at ID19, the inset shows a photo of the experimental hutch [15]. The reflective optical element (OE) is mounted on the so-called high-resolution tomograph, its detector can be translated along the beam over a travel range of 1 m. A second detector at the end of the hutch is used to grab a picture of the beam profile. Details of the mount for the optical element under study are shown in Figure 2.

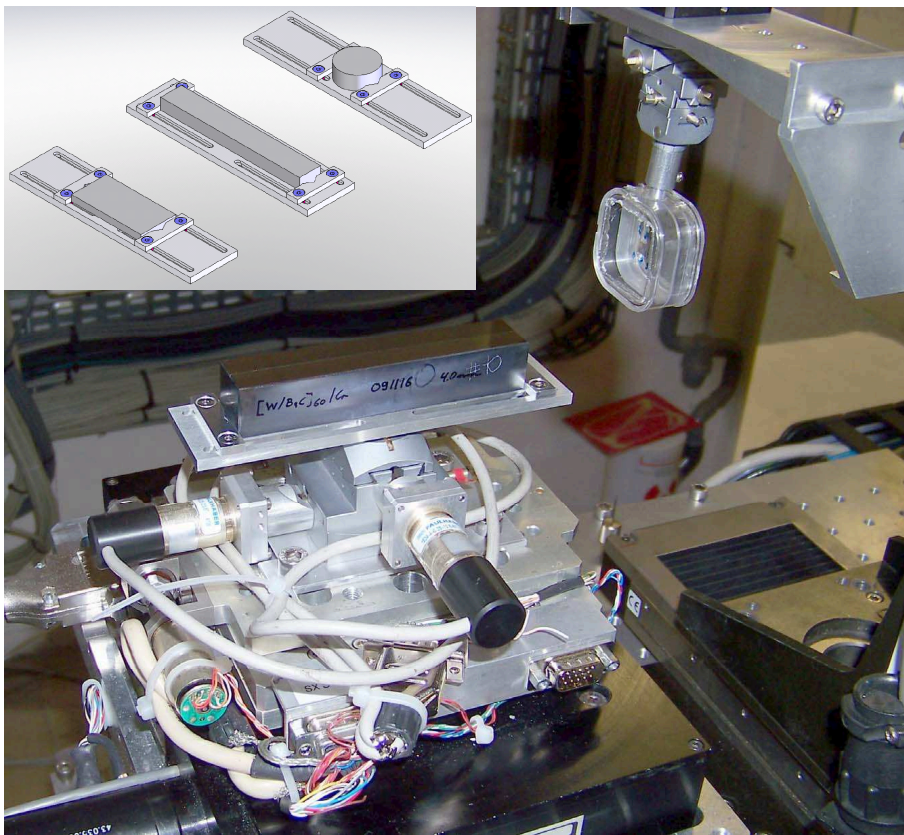


Figure 2: [1-column-span, color online only] The mount for the optical element (here shown with a multilayer mirror in the center of the picture): an aluminium plate with shiftable bars which can be tightened in order to fix the element without introducing mechanical stress. Below a double-cradle system to align the roll as well as to chose the incidence angle. The inset shows a sketch of the mount for different substrate geometries. In the upper right part of the image, the phase grating can be seen, mounted in a protective box on a diffractometer head as well as on horizontal and vertical translation stages.

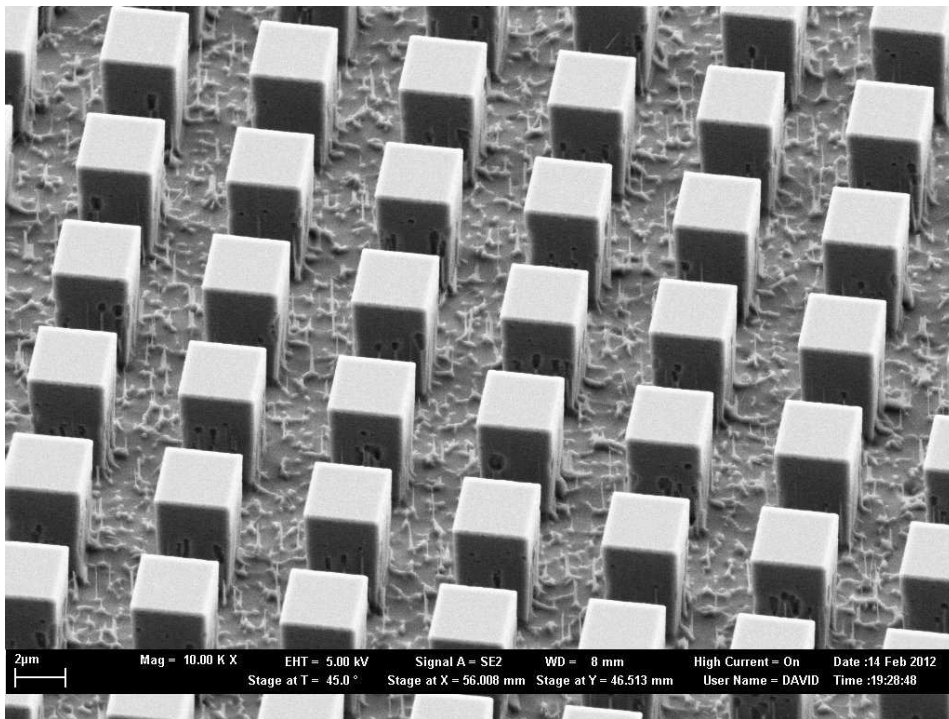


Figure 3: [1-column-span] Scanning-electron microscopy of the phase-grating used as test pattern to measure the coherence properties of the reflected beam.

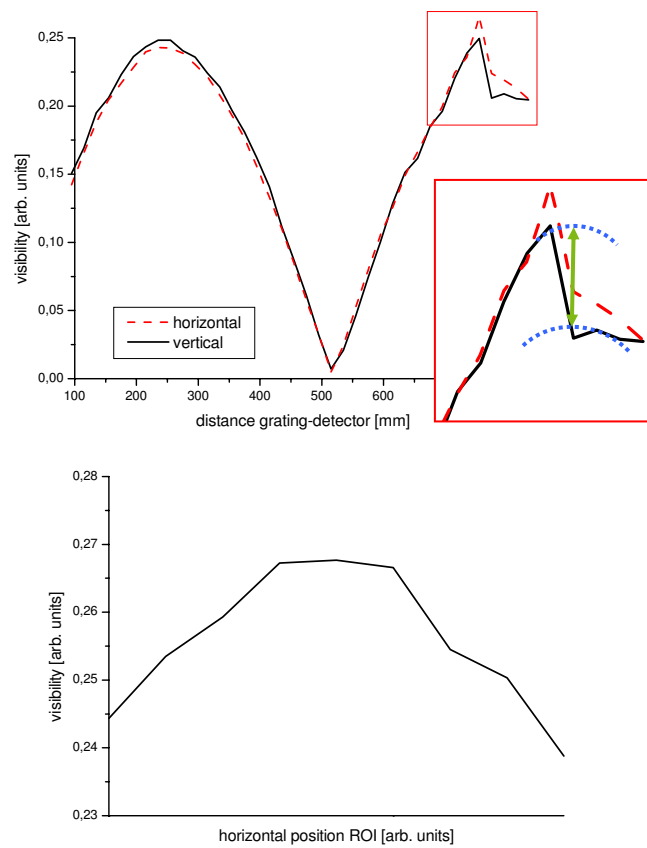


Figure 4: [1-column-span, color online only] Top: change of the visibility during a scan due to a refill marked in red (red box with zoomed inset: dotted lines depict the approximated curves, the arrow marks the absolute drop in intensity). Bottom: variation of the measured visibility due to different regions-of-interest selected along the middle horizontal line of the field-of-view of the deployed indirect detector.

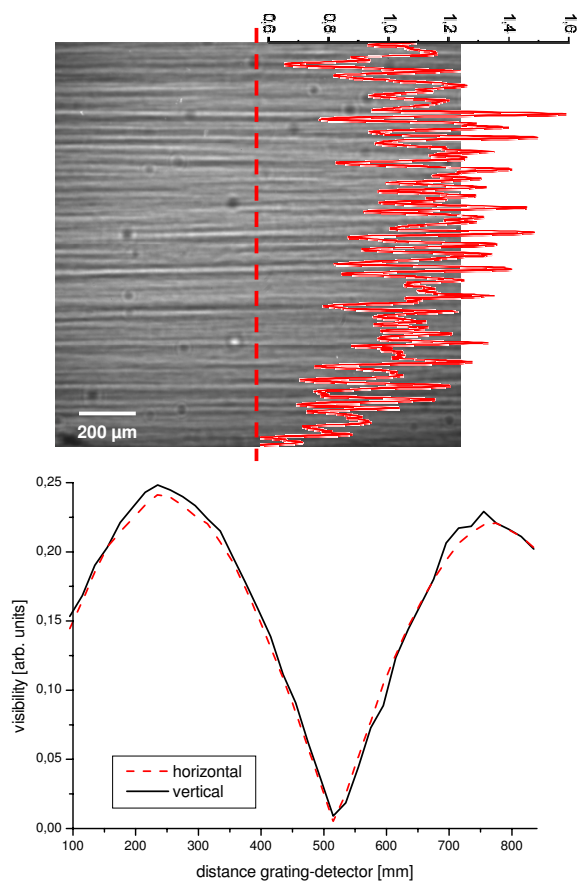


Figure 5: [1-column-span, color online only] Results of the characterization of a W/B₄C multilayer mirror (2.0 nm d spacing, 120 bilayers, ESRF multilayer laboratory). Top: the beam profile after 6.1 m of propagation. A profile plot of the marked line (normalised to the mean gray-value of the image) is used as a measure of the intensity modulation. Bottom: plot of the horizontal and vertical visibility of the phase grating measured at different propagation distances. The respective angular source sizes as derived from the two Talbot distances given are: 1.54 μrad (horizontal) × 1.69 μrad (vertical).